

Fig. 1

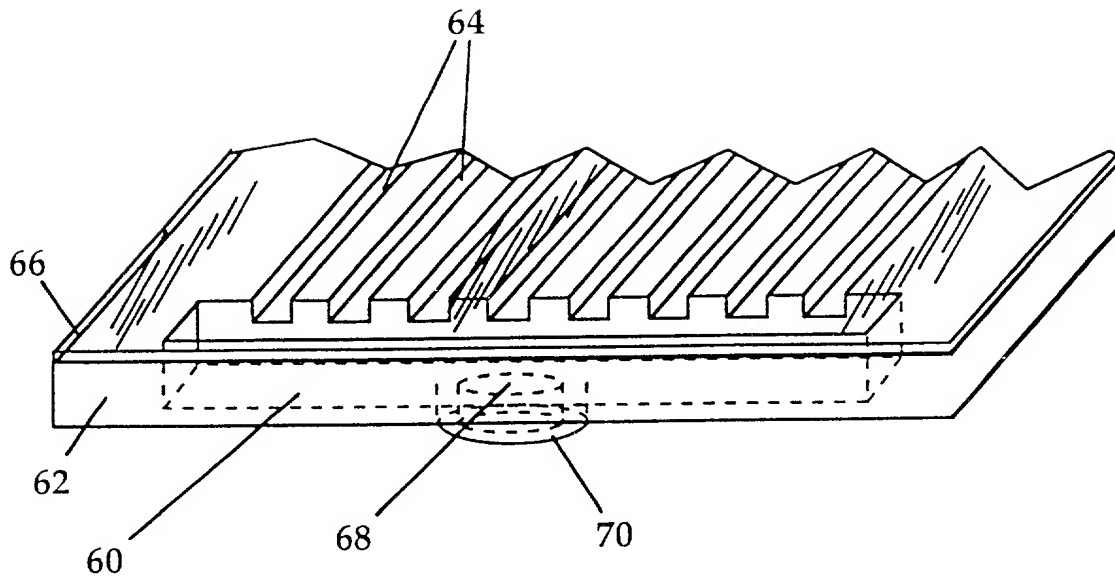


Fig. 2

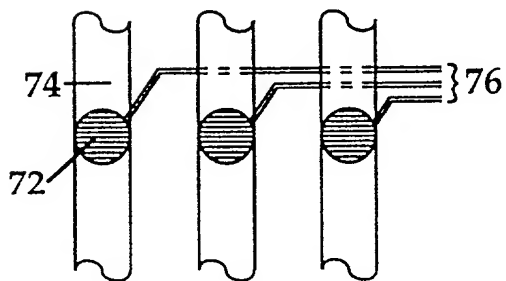


Fig. 3A

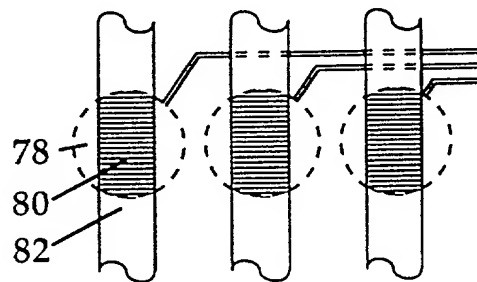


Fig. 3B

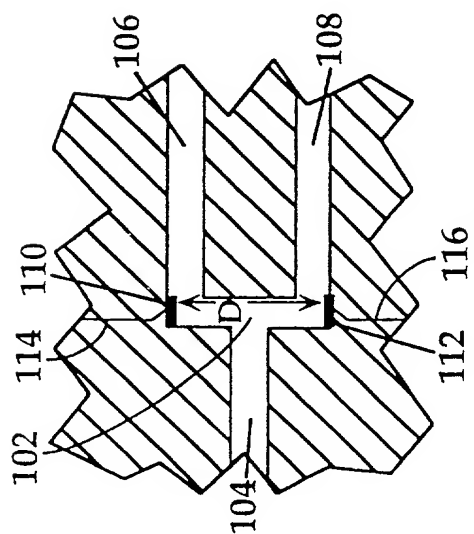


Fig. 4A

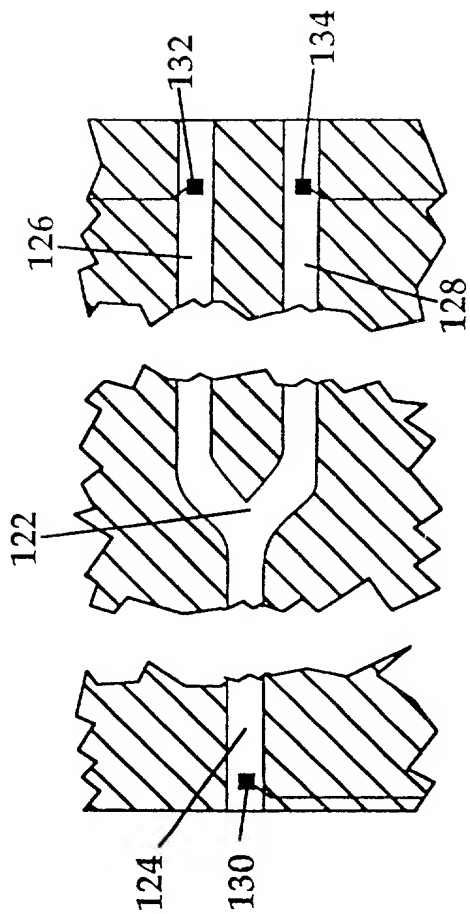


Fig. 4B

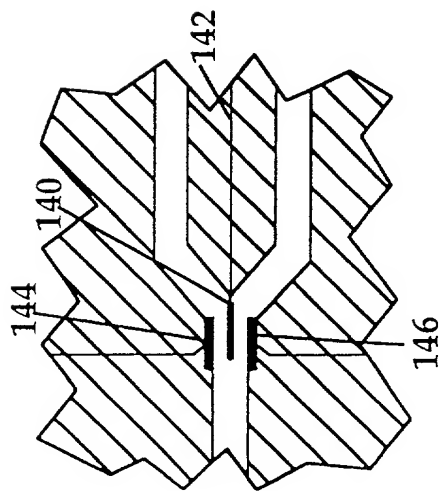


Fig. 4C

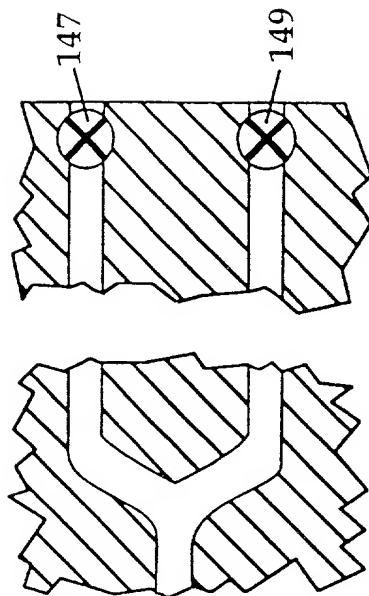


Fig. 4D

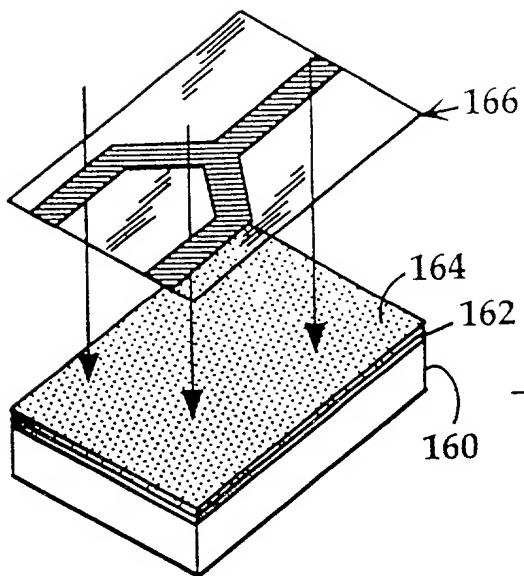


Fig. 5A

develop
and rinse

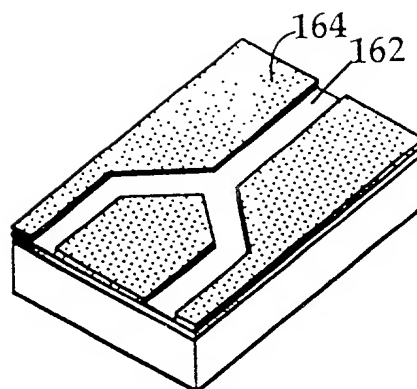


Fig. 5B

1. etch SiO_2
2. remove resist

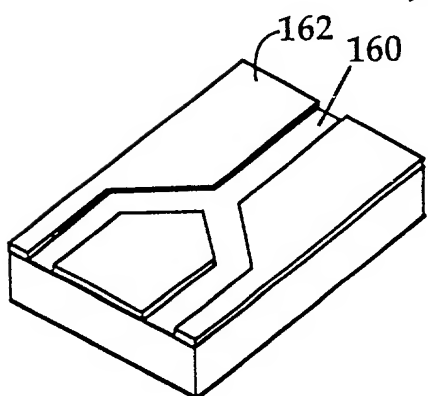


Fig. 5C

etch Si

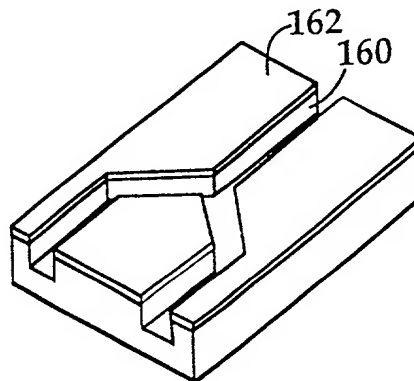


Fig. 5D

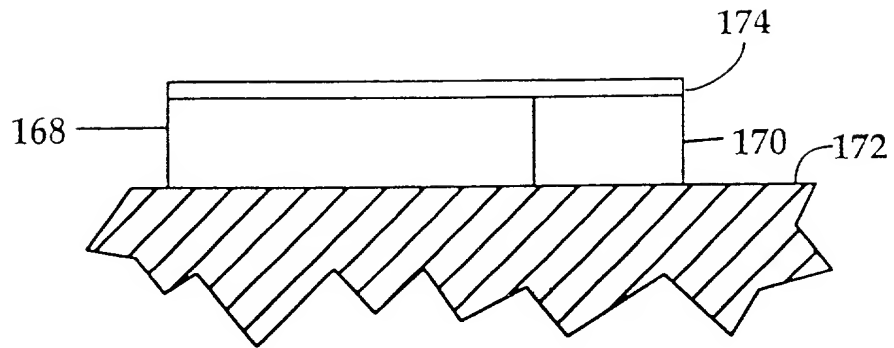


Fig. 6A

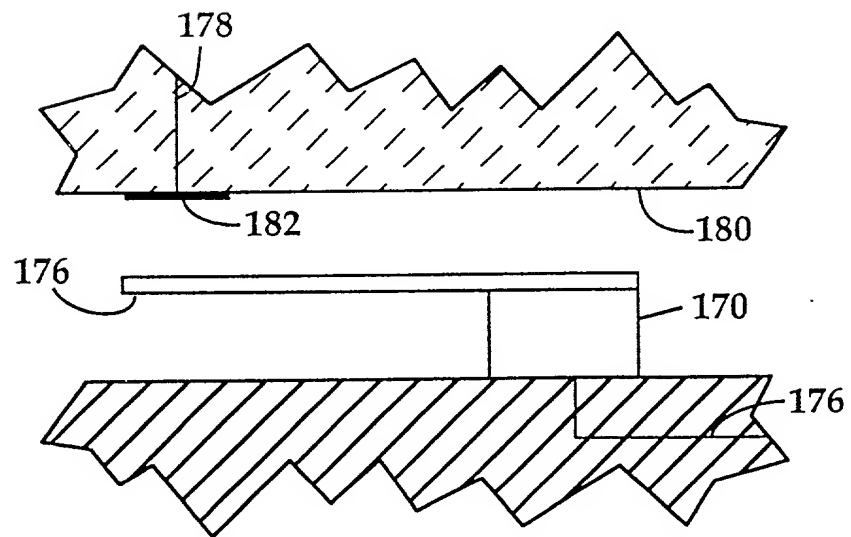


Fig. 6B

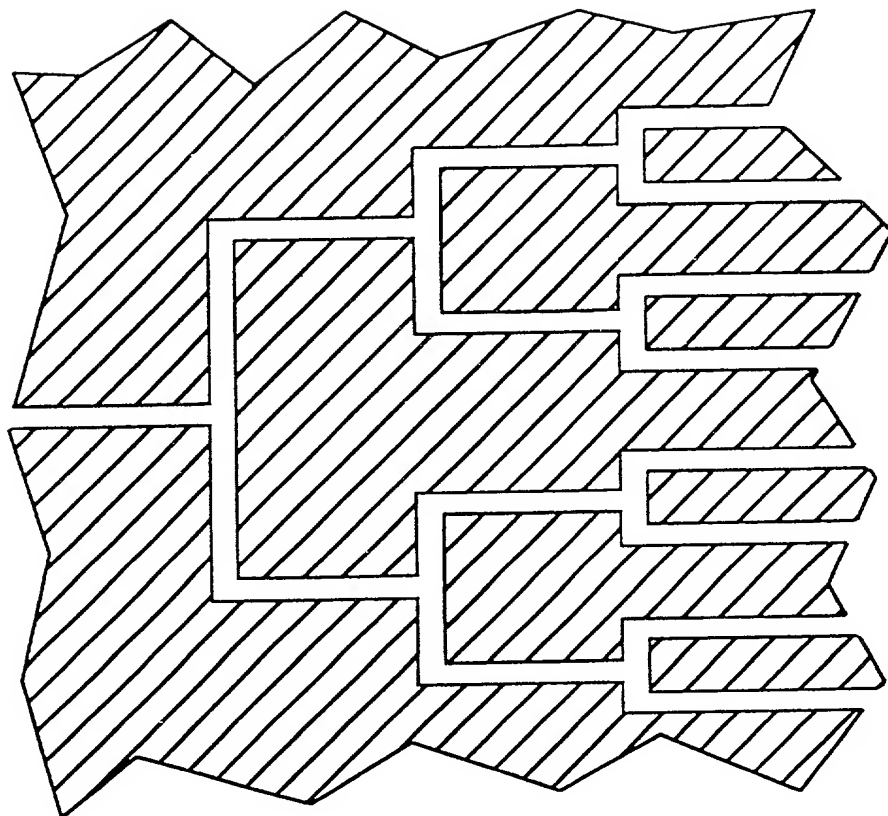


Fig. 7